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Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

Listing of Claims:

1. (Previously Presented) A carrier head for chemical mechanical polishing, comprising:

a base having at least a portion formed of a polymer;

- a mounting assembly connected to the base having a surface for contacting a substrate;
- a retainer secured to the portion of the base to prevent the substrate from moving along the surface; and
- a damping material secured between the retainer and the portion of the base to reduce the translation of vibrational energy between the retainer and the base.
- 2. (Original) The carrier head of claim 1, wherein the portion of the base is a ring-shaped body extended around a perimeter of the base.
- 3. Cancelled.
- 4. (Previously Presented) The carrier head of claim 2, wherein the ring-shaped body includes at least one boss extending to contact the retainer.
- 5. (Previously Presented) The carrier head of claim 4, further comprising at least one screw extending through apertures in the base, the ring-shaped body and the damping material and into a receiving recess in the retainer to secure the retainer to the base.

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6. (Previously Presented) The carrier head of claim 5, wherein the at least one boss surrounds the at least one screw.

- 7. (Previously Presented) The carrier head of claim 1, wherein the polymer includes polyphenylenesulfide, carbon fibers and polytetrafluoroethylene.
- 8. (Original) The carrier head of claim 7, wherein the polymer includes about 50-55% polyphenylenesulfide, 30-35% carbon fibers, and about 10-15% polytetrafluoroethylene.
- 9. (Previously Presented) The carrier head of claim 7, wherein the damping material includes a polyvinylchoride thermoplastic.
- 10. (Previously Presented) The carrier head of claim 2, wherein the polymer includes polyphenylenesulfide, carbon fibers and polytetrafluoroethylene.
- 11. (Original) The carrier head of claim 1, wherein the entire base is formed from the polymer.
- 12. Cancelled.
- 13. (Previously Presented) The carrier head of claim 1, wherein a bottom portion of the retainer includes at least one of carbon, fluoropolymer, or polyester.
- 14. (Previously Presented) A carrier head for chemical mechanical polishing, comprising:
 - a base;
 - a mounting assembly attached to the base having a surface for contacting a substrate;
 - a retainer secured to the base to prevent the substrate from moving along the surface; and

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a damping material secured between the retainer and the base to reduce the translation of vibrational energy between the retainer and the base.

- 15. (Previously Presented) The carrier head of claim 14, wherein the damping material includes at least one of polyurethane or polyvinylchoride thermopolastic.
- 16. (Original) The carrier head of claim 14, wherein the base has at least a portion formed of a polymer and the retainer is secured to the portion of the base.
- 17. (Original) The carrier head of claim 16, wherein the portion of the base is a ring-shaped body extended around a perimeter of the base.
- 18. (Previously Presented) The carrier head of claim 17, further comprising at least one screw extending through apertures in the base, the ring-shaped body and the damping material and into a receiving recess in the retainer to secure the retainer to the base.
- 19. (Previously Presented) The carrier head of claim 17, wherein the ring-shaped body includes at least one boss surrounding the screw and extending to contact the retainer.
- 20. (Previously Presented) The carrier head of claim 14, wherein a bottom portion of the retainer includes at least one of carbon, fluoropolymer, or polyester.
- (Currently Amended) A carrier head for chemical mechanical polishing, comprising:
 a base;
- a mounting assembly attached to the base having a surface for contacting a substrate; and a retainer secured to the base to prevent the substrate from moving along the surface, at least a bottom portion of the retainer including a material selected from the group consisting of polytetrafluoroethylene, perfluoroalkoxy, polyetherketoneketone, polybenzimidazole, an

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imidized thermoset polyimide, a semi-crystalline thermoplastic polyester, and a long molecular chain molecule produced from poly-paraphenylene terephthalamide.

- 22. (Previously Presented) The carrier head of claim 21, wherein the bottom portion of the retainer further includes carbon.
- 23. (Withdrawn) The carrier head of claim 22, wherein the bottom portion of the retainer further includes graphite.
- 24. (Previously Presented) The carrier head of claim 22, wherein the bottom portion of the retainer further includes carbon fibers.

Claims 25-28. Cancelled.

29. (Currently Amended) A retaining ring for a chemical mechanical polishing head, comprising:

an upper portion configured to be secured to a base;

- a bottom portion that includes a material selected from the group consisting of polytetrafluoroethylene, perfluoroalkoxy, polyetherketoneketone, polybenzimidazole, a semi-crystalline thermoplastic polyester, and a long molecular chain molecule produced from polyparaphenylene terephthalamide.
- 30. (Withdrawn) The retaining ring of claim 29, wherein the bottom portion of the retaining ring further includes at least one of graphite or carbon fibers.
- 31. (New) The carrier head of claim 21, wherein at least a bottom portion of the retainer includes perfluoroalkoxy.

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32. (New) The carrier head of claim 21, wherein at least a bottom portion of the retainer includes polyetherketoneketone.

- 33. (New) The carrier head of claim 21, wherein at least a bottom portion of the retainer includes polybenzimidazole.
- 34. (New) The carrier head of claim 21, wherein at least a bottom portion of the retainer includes a semi-crystalline thermoplastic polyester.
- 35. (New) The carrier head of claim 21, wherein at least a bottom portion of the retainer includes a long molecular chain molecule produced from poly-paraphenylene terephthalamide.
- 36. (New) The carrier head of claim 21, wherein at least a bottom portion of the retainer includes an imidized thermoset polyimide.
- 37. (New) The retaining ring of claim 29, wherein the bottom portion includes perfluoroalkoxy.
- 38. (New) The retaining ring of claim 29, wherein the bottom portion includes polyetherketoneketone.
- 39. (New) The retaining ring of claim 29, wherein the bottom portion includes polybenzimidazole.
- 40. (New) The retaining ring of claim 29, wherein the bottom portion includes a semicrystalline thermoplastic polyester.

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41. (New) The retaining ring of claim 29, wherein the bottom portion includes a long molecular chain molecule produced from poly-paraphenylene terephthalamide.